INF5490 RF MEMS

L10: RF MEMS resonators II

S2008, Oddvar Søråsen Department of Informatics, UoO

Today's lecture

Lateral vibrating resonator:
 Comb resonator

- Working principle
- Detailed modeling
 - A) "phasor"-modeling
 - B) modeling by converting between mechanical and electrical energy domains

Lateral and vertical movement

- Lateral movement in the resonator
 - Parallel to substrate
 - Folded beam comb structure
- Vertical movement (next lecture)
 - Vertical to substrate
 - Clamped-clamped beam (c-c beam)
 - free-free beam (f-f beam)

Comb resonator

- Fixed comb + movable, suspended comb
- Suspended by folded springs, compact layout
- Total capacitance between the combs can be varied
- Applied bias (+ or -) generates an electrostatic force between left anchor-comb and "shuttle"-comb. Shuttle pulled to the left in the plane

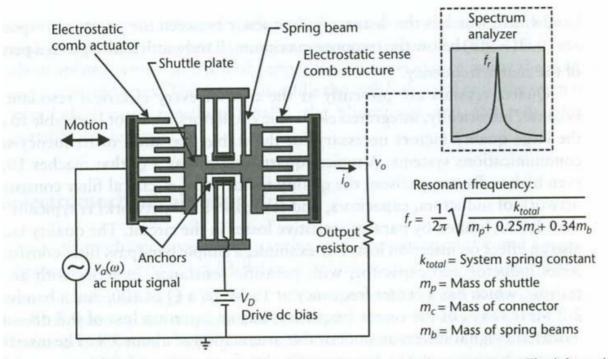
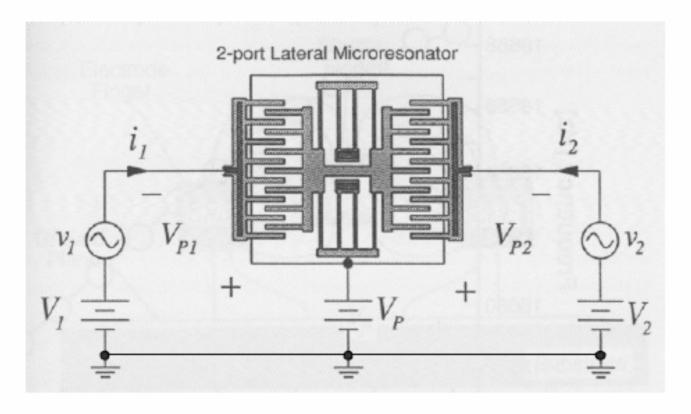


Figure 7.9 Illustration of a micromachined folded-beam comb-drive resonator. The left comb drive actuates the device at a variable frequency ω . The right capacitive-sense-comb structure measures the corresponding displacement by turning the varying capacitance into a current, which generates a voltage across the output resistor. There is a peak in displacement, current, and output voltage at the resonant frequency.

Detailed modeling

- Modeling of lateral comb structure
 - "Phasor"-modeling ala UoC, Berkeley
 - Detailed calculations included
 - Conversion between energy domains
 - Material from UCLA
- In lecture L11 the c-c beam will be modeled with reference to the book
 - T. Itoh et al: RF Technologies for Low Power Wireless
 Communications", chap. 12: "Transceiver Front-End Architectures Using Vibrating Micromechanical Signal Processors", by Clark T.-C. Nguyen

The Lateral Resonator as a "Two-Port"



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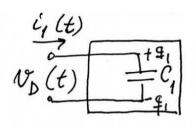
C. T.-C. Nguyen, Ph.D. Thesis, EECS Dept., UC Berkeley, 1994

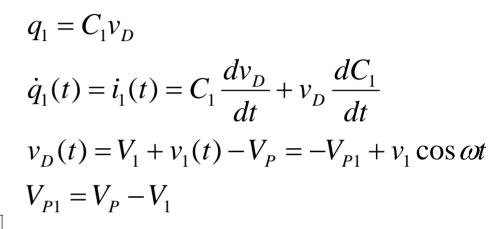
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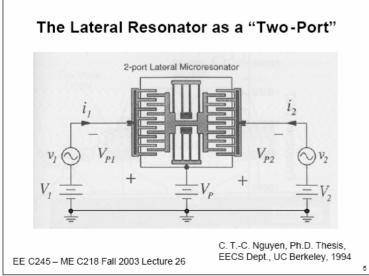
Calculation procedure

- A. Model the comb is a two-port. Analyze first the input port
- B. When the comb moves the input capacitance will have a static and a variable component
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- K. Set up a complete two-port-model

A. Model the comb is a two-port. Analyze first the input port

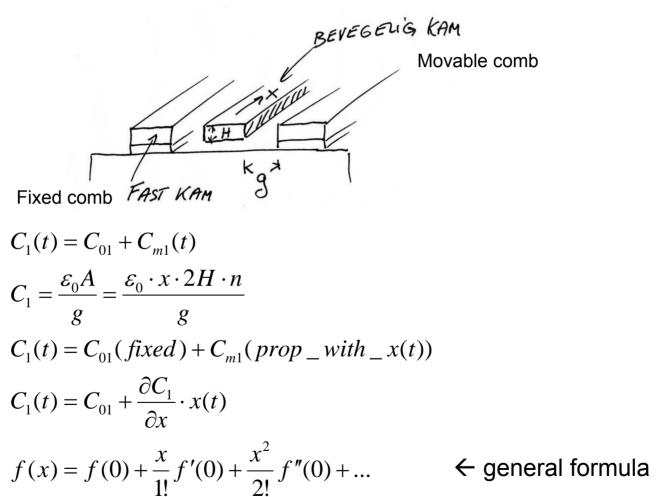






 V_{P1} = positive when $V_P > V_1$

B. When the comb moves the input capacitance will have a static and variable component



C. Find the input current versus displacement, X

$$\begin{split} i_{1}(t) &= C_{1} \frac{dv_{D}}{dt} + v_{D} \frac{dC_{1}}{dt} \\ &= C_{1} \frac{dv_{1}(t)}{dt} + (-V_{P1} + v_{1}(t)) \frac{\partial C_{1}}{\partial x} \frac{\partial x}{\partial t} = \left[C_{01} + \frac{\partial C_{1}}{\partial x} \cdot x(t) \right] \frac{dv_{1}(t)}{dt} + \dots \\ &= C_{01} \frac{dv_{1}(t)}{dt} + \frac{\partial C_{1}}{\partial x} \cdot x(t) \cdot \frac{\partial v_{1}(t)}{\partial t} - V_{P1} \frac{\partial C_{1}}{\partial x} \frac{\partial x}{\partial t} + v_{1}(t) \frac{\partial C_{1}}{\partial x} \frac{\partial x}{\partial t} \\ &= C_{01} \frac{dv_{1}(t)}{dt} + \frac{\partial C_{1}}{\partial x} \left(x \cdot \frac{\partial v_{1}}{\partial t} + v_{1} \frac{\partial x}{\partial t} \right) - V_{P1} \frac{\partial C_{1}}{\partial x} \frac{\partial x}{\partial t} \\ &= C_{01} \frac{\partial v_{1}(t)}{\partial t} + \frac{\partial C_{1}}{\partial x} \left(x \cdot \frac{\partial v_{1}}{\partial t} + v_{1} \frac{\partial x}{\partial t} \right) - V_{P1} \frac{\partial C_{1}}{\partial x} \frac{\partial x}{\partial t} \\ &= C_{02} \frac{\partial v_{1}(t)}{\partial t} + \frac{\partial v_{2}(t)}{\partial x} \left(x \cdot \frac{\partial v_{1}}{\partial t} + v_{1} \frac{\partial x}{\partial t} \right) - V_{P1} \frac{\partial c_{1}}{\partial x} \frac{\partial x}{\partial t} \\ &= C_{03} \frac{\partial v_{1}(t)}{\partial t} + \frac{\partial v_{2}(t)}{\partial x} \left(x \cdot \frac{\partial v_{1}}{\partial t} + v_{1} \frac{\partial x}{\partial t} \right) - V_{P1} \frac{\partial c_{1}}{\partial x} \frac{\partial x}{\partial t} \\ &= C_{03} \frac{\partial v_{1}(t)}{\partial t} + \frac{\partial v_{2}(t)}{\partial x} \left(x \cdot \frac{\partial v_{1}}{\partial t} + v_{1} \frac{\partial x}{\partial t} \right) - V_{P1} \frac{\partial c_{1}}{\partial x} \frac{\partial x}{\partial t} \\ &= C_{03} \frac{\partial v_{1}(t)}{\partial t} + \frac{\partial v_{2}(t)}{\partial x} \left(x \cdot \frac{\partial v_{1}}{\partial t} + v_{1} \frac{\partial x}{\partial t} \right) - V_{P1} \frac{\partial c_{1}}{\partial x} \frac{\partial x}{\partial t} \\ &= C_{03} \frac{\partial v_{1}(t)}{\partial t} + \frac{\partial v_{2}(t)}{\partial x} \left(x \cdot \frac{\partial v_{1}}{\partial t} + v_{1} \frac{\partial x}{\partial t} \right) - V_{P1} \frac{\partial v_{2}(t)}{\partial x} \frac{\partial v_{2}(t)}{\partial t} \\ &= C_{03} \frac{\partial v_{1}(t)}{\partial t} + \frac{\partial v_{2}(t)}{\partial x} \left(x \cdot \frac{\partial v_{1}(t)}{\partial t} + v_{1} \frac{\partial v_{2}(t)}{\partial t} \right) - V_{P1} \frac{\partial v_{2}(t)}{\partial x} \frac{\partial v_{2}(t)}{\partial t} \\ &= C_{03} \frac{\partial v_{1}(t)}{\partial t} + \frac{\partial v_{2}(t)}{\partial x} \left(x \cdot \frac{\partial v_{1}(t)}{\partial t} + v_{2} \frac{\partial v_{2}(t)}{\partial t} \right) - V_{P2} \frac{\partial v_{2}(t)}{\partial x} \frac{\partial v_{2}(t)}{\partial t} \\ &= C_{03} \frac{\partial v_{2}(t)}{\partial t} + \frac{\partial v_{2}(t)}{\partial t} + \frac{\partial v_{2}(t)}{\partial t} + v_{2} \frac{\partial v_{2}(t)}{\partial t} \\ &= C_{03} \frac{\partial v_{2}(t)}{\partial t} + v_{2} \frac{\partial v_{2}(t)}{\partial t} + v_{2} \frac{\partial v_{2}(t)}{\partial t} + v_{2} \frac{\partial v_{2}(t)}{\partial t} \\ &= C_{03} \frac{\partial v_{2}(t)}{\partial t} + v_{2} \frac{\partial v_{2}(t)}{\partial t} + v_{2} \frac{\partial v_{2}(t)}{\partial t} + v_{2} \frac{\partial v_{2}(t)}{\partial t} \\ &= C_{03} \frac{\partial v_{2}(t)}{\partial t} + v_{2} \frac{\partial v_{2}(t)}{\partial t} \\ &= C_{03} \frac{\partial v_{2}(t)}{\partial t} + v_{2} \frac{\partial v_{2}(t)}{\partial t}$$

double frequency, small contribution

$$i_1(t) \approx C_{01} \frac{\partial v_1(t)}{\partial t} - V_{P1} \frac{\partial C_1}{\partial x} \frac{\partial x(t)}{\partial t}$$

Current into the DC-capacitance

"motional current"

$$V_{1}(t)$$
 $V_{1}(t)$
 $V_{2}(t)$
 $V_{3}(t)$
 $V_{4}(t)$
 $V_{5}(t)$
 $V_{7}(t)$
 $V_{7}(t)$

$$\begin{split} i_{1x}(t) &= -V_{P1} \frac{\partial C_1}{\partial x} \frac{\partial x(t)}{\partial t} = (-V_{P1} \frac{\partial C_1}{\partial t}) & \text{"motional current"} \\ I_{1x}(j\omega) &= -V_{P1} \frac{\partial C_1}{\partial x} \cdot j\omega \cdot X(j\omega) & \text{phasor-form of "motional current"} \end{split}$$

= current as function of movement ("displacement")

D. Calculate the input admittance, Y ("motional admittance")

D1. Find Y versus X

$$V_{1}(j\omega) \xrightarrow{Co1} I_{1x}(j\omega)$$

$$V_{2}(j\omega) \xrightarrow{Co1} I_{2}(j\omega)$$

$$Y_{1x}(j\omega) = \frac{I_{1x}(j\omega)}{V_1(j\omega)} = -V_{P1} \frac{\partial C_1}{\partial x} \cdot j\omega \cdot \frac{X(j\omega)}{V_1(j\omega)}$$
 voltage

D2. X depends on the electrostatic force, F, and m, b and k

$$Y_{1x}(j\omega) = -V_{P1} \frac{\partial C_1}{\partial x} \cdot j\omega \cdot \frac{X(j\omega)}{F_d(j\omega)} \cdot \frac{F_d(j\omega)}{V_1(j\omega)}$$

D3. F depends on the applied bias, V

Relationship between force and voltage can be found from:

$$U = \frac{1}{2}C_1 v_D^2(t)$$

Potential energy, V_D is independent of x

$$F = \frac{\partial U}{\partial x} = \frac{1}{2} v_D^2(t) \cdot \frac{\partial C_1}{\partial x}$$

non-linear relation

$$F = F_0 + f \cos \omega t$$
, $v_D = -V_{P1} + v_1 \cos \omega t$

Linearizing around a DC-point

$$F_0 + f \cos \omega t = \frac{1}{2} (-V_{P1} + v_1 \cos \omega t)^2 \cdot \frac{\partial C_1}{\partial x}$$
 Substitute

$$= \frac{1}{2} (V_{P1}^2 - 2 \cdot V_{P1} \cdot v_1 \cos \omega t + v_1^2 \cos^2 \omega t) \cdot \frac{\partial C_1}{\partial x}$$

 $\cos 2\omega t - term$

$$f\cos\omega t = -V_{P1} \cdot v_1 \cos\omega t \cdot \frac{\partial C_1}{\partial x}$$
 Comparing AC-terms

$$f_{d,\omega} = -V_{P1} \frac{\partial C_1}{\partial x} v_1(t)$$

← LINEAR RELATION!

$$F_{d}(j\omega) = -V_{P1} \frac{\partial C_{1}}{\partial x} \cdot V_{1}(j\omega)$$
 In phasor-form
$$\frac{F_{d}(j\omega)}{V_{1}(j\omega)} = -V_{P1} \frac{\partial C_{1}}{\partial x}$$

Relation between displacement and force:

$$\frac{X(s)}{F_d(x)} = \frac{1}{ms^2 + bs + k} = \frac{1}{k} \frac{k/m}{s^2 + \frac{b}{m}s + \frac{k}{m}}$$

 $\frac{X(s)}{F_d(x)} = \frac{1}{ms^2 + bs + k} = \frac{1}{k} \frac{k/m}{s^2 + \frac{b}{m}s + \frac{k}{m}}$ D2. X depends on the electrostatic force, F, and m, b and k

$$\omega_0^2 = k/m, \ b/m = \omega_0/Q$$

$$Q = \frac{\sqrt{k/m}}{b/m} = \frac{\sqrt{km}}{b}$$

Substitute

$$\frac{X(s)}{F_d(s)} = \frac{1}{k} \cdot \frac{\omega_0^2}{s^2 + \frac{\omega_0}{Q} s + \omega_0^2} \rightarrow_{s=j\omega} \frac{1}{k} \cdot \frac{\omega_0^2}{(\omega_0^2 - \omega^2) + j \frac{\omega_0 \omega}{Q}}$$

$$\frac{X(j\omega)}{F_d(j\omega)} = \frac{1}{k} \cdot \frac{1}{\left[1 - (\omega/\omega_0)^2\right] + j \frac{\omega}{Q\omega_0}}$$

E. Find an expression for Y (dynamic behavior)

$$\begin{split} Y_{1x}(j\omega) &= -V_{P1} \frac{\partial C_1}{\partial x} \cdot j\omega \cdot \frac{X(j\omega)}{F_d(j\omega)} \cdot \frac{F_d(j\omega)}{V_1(j\omega)} \\ &= -V_{P1} \frac{\partial C_1}{\partial x} \cdot j\omega \cdot \frac{1/k}{\left[1 - (\omega/\omega_0)^2\right] + j\frac{\omega}{\omega_0 Q}} \cdot (-V_{P1} \frac{\partial C_1}{\partial x}) \end{split}$$

$$\eta = V_{P1} \frac{\partial C_1}{\partial x}$$

$$Y_{1x}(j\omega) = \eta^2 \cdot j\omega \cdot \frac{1/k}{\left[1 - (\omega/\omega_0)^2\right] + j\frac{\omega}{\omega_0 Q}}$$

$$I_{1x}(j\omega) = [\ldots] \cdot V_1(j\omega)$$

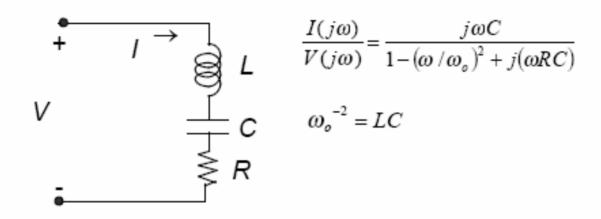
← η defined

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F. Series L-C-R Admittance

The current through an *L-C-R* branch is:



Match terms in motional admittance → find equivalent elements

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Current through the L-C-R-circuit

$$+ \bigvee_{-3} I_{-3} I_{-3} V$$

$$V = 0$$

$$V$$

$$V = I(sL+1/sC+R)$$

$$V = I(sL+1/sC+R)$$

$$\frac{I(s)}{V(s)} = \frac{sC}{s^2LC+sRC+1}$$

$$Y(j\omega) = \frac{I(j\omega)}{V(j\omega)} = \frac{j\omega C}{-\omega^2LC+j\omega RC+1}$$

$$\omega_0^2 = \frac{1}{LC}, \ \omega_0 = \frac{1}{\sqrt{LC}}$$

$$Y(j\omega) = \frac{j\omega C}{\left[1 - (\omega/\omega_0)^2\right] + j\omega RC} = \frac{j\omega C}{\left[...\right] + j\frac{\omega}{\omega_0 Q}}$$

$$RC = \frac{1}{\omega_0 Q}, \ Q = \frac{1}{\omega_0 RC} = \frac{\sqrt{LC}}{RC} = \sqrt{\frac{L}{C}} \cdot \frac{1}{R}$$

$$Y(j\omega) = \frac{j\omega C}{\left[1 - (\omega/\omega_0)^2\right] + j\frac{\omega}{\omega_0 Q}}$$

Compare to

$$Y_{1x}(j\omega) = \eta^2 \cdot \frac{j\omega \cdot 1/k}{\left[1 - (\omega/\omega_0)^2\right] + j\frac{\omega}{\omega_0 Q}}$$

This results in:

$$C_{x1} = \eta^2 / k$$

$$\omega_0^2 = k / m = 1 / LC \Rightarrow L_{x1} = \frac{1}{C} \cdot \frac{m}{k} = \frac{k}{\eta^2} \cdot \frac{m}{k} = \frac{m}{\eta^2}$$

$$RC = \frac{1}{Q\omega_0} = \frac{1}{Q\sqrt{k/m}} \Rightarrow R_{x1} = \frac{1}{C} \cdot \frac{1}{Q\sqrt{k/m}} = \frac{k}{\eta^2} \frac{\sqrt{m}}{Q\sqrt{k}} = \frac{\sqrt{km}}{Q\eta^2}$$

 η = Electromagnetic coupling coefficient

$$I_{x1}(\omega_0) = \frac{V_1(\omega_0)}{R_{x1}}$$
 At resonance the impedances from L and C cancel

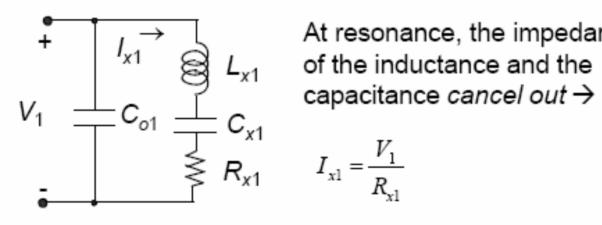
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G. Equivalent Circuit for Input Port

A series L-C-R circuit results in the identical expression -> find equivalent values L_{x1} , C_{x1} , and R_{x1}

$$L_{\rm xl} = \frac{m}{\eta^2} \qquad C_{\rm xl} = \frac{\eta^2}{k} \qquad R_{\rm xl} = \frac{\sqrt{km}}{Q\eta^2} \qquad \qquad \eta = V_{\rm Pl} \frac{\partial C_1}{\partial x} = \ {\rm electromechanical \ coupling \ coefficient}$$



At resonance, the impedances

$$I_{x1} = \frac{V_1}{R_{x1}}$$

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H. Find the output current for a given input

$$i_{1x}(t) = -V_{P1} \frac{\partial C_1}{\partial t}$$

This displacement causes the output capacitance C2 also to change. Output current due to displacement ($v_2 = 0V$, short-circuited):

$$i_2(t) = -V_{P2} \frac{\partial C_2}{\partial t} = -V_{P2} \frac{\partial C_2}{\partial x} \frac{\partial x}{\partial t}$$

$$I_{2}(j\omega) = -V_{P2} \frac{\partial C_{2}}{\partial x} \cdot j\omega \cdot X(j\omega)$$
 In phasor-form
$$X(j\omega) = \frac{1/k}{\left[1 - (\omega/\omega_{0})^{2}\right] + j\frac{\omega}{\omega_{0}Q}} \cdot F_{d}(j\omega)$$

$$F_d(j\omega) = -V_{P1} \frac{\partial C_1}{\partial x} \cdot V_1(j\omega)$$
 voltage \rightarrow force \rightarrow displacement \rightarrow current

$$\Rightarrow I_{2}(j\omega) = \frac{V_{P1}V_{P2} \frac{\partial C_{1}}{\partial x} \frac{\partial C_{2}}{\partial x}}{\left[1 - (\omega/\omega_{0})^{2}\right] + j\frac{\omega}{\omega_{0}Q}} \cdot j\omega \cdot (1/k) \cdot V_{1}(j\omega)$$

L. Calculate the ratio between the output and input currents ("forward current gain")

"Forward current gain"

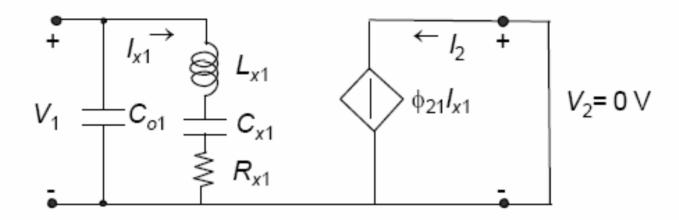
$$\Phi_{21} = \frac{I_2(j\omega)}{I_{x1}(j\omega)} = \frac{-V_{P2}\frac{\partial C_2}{\partial x} \cdot j\omega \cdot X(j\omega)}{-V_{P1}\frac{\partial C_1}{\partial x} \cdot j\omega \cdot X(j\omega)} = \frac{V_{P2}\frac{\partial C_2}{\partial x}}{V_{P1}\frac{\partial C_1}{\partial x}}$$

$$I_2(j\omega) = \Phi_{21} \cdot I_{x1}(j\omega), \ V_2 = 0$$

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J. Two-Port Equivalent Circuit $(v_2 = 0)$



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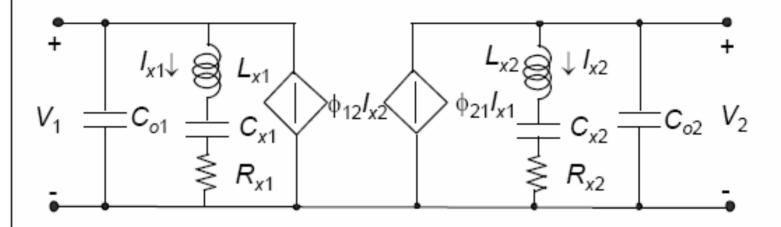
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K.

Complete Two-Port Model



Symmetry implies that modeling can be done from port 2, with port 1 shorted → superimpose the two models

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Equivalent Circuit for Symmetrical Resonator ($\phi_{21} = \phi_{12} = 1$) C. T.-C. Nguyen, Ph.D., φ12 ix2 φ₂₁ i_{x1} UC Berkeley, 1994 Lx1 Cx1 Rx1 Rx2 Cx2 Lx2 $C_x = 0.5 \, fF$ $L_x = 200 \text{ kH}$ $R_x = 500 \text{ k}\Omega$ $C_{oi}, C_{oo} = 15 \text{ fF}$

Alternative modeling

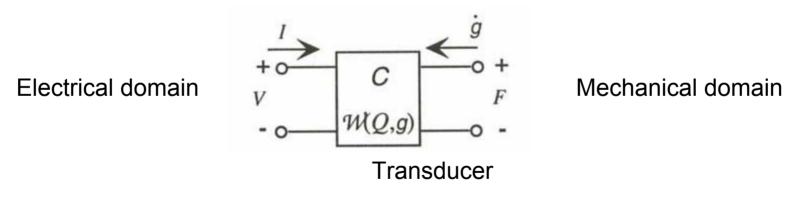
- Exploit conversion between mechanical and electrical energy domains
 - Slides from UCLA

Supported by lecture notes ->

Two-Port Micromechanical Resonator **Using Comb-Drive Actuator** 2-port Lateral Microresonator M. C. Wu EE M260B / MAE M282 / BME M260B 15

Conversion between energy domains

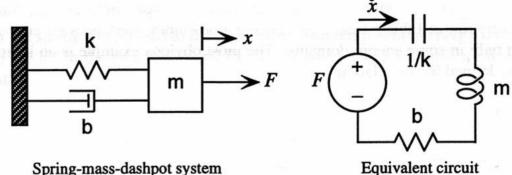
 Both vertical and lateral resonator structures may be described by a generalized non-linear capacitance, C, interconnecting energydomains



Interconnecting where there is **no energy loss**

Procedure

- First, transform the mechanical domain impedances to an electrical representation
 - The mechanical components are modeled as lumped electrical components
- NB! You are still in the mechanical domain!
 - C = 1/k
 - -L=m
 - -R=b



- Power-variables
 - Effort = force → voltage
 - Flow = velocity → current

Interconnecting different energy domains

- 1. Each energy domain is transformed to its electrical equivalent
- 2. Domains are interconnected by a generalized nonlinear capacitance, C
- 3. Transformer and gyrator may be used for interconnecting if a linear relationship exists between the power-variables!
 - Problem: Transducer C is generally NOT a linear 2-port
- 4. Must linearize the 2-port transducer to be able to substitute it with a transformer
- 5. The transformer can "be removed" by recalculating the component **values** to **new** ones
 - − → Electromechanical coupling coefficient used! = turn ratio
 - → Results in a common circuit diagram

Interaction between energy domains

- Suppose linear relation between power variables
 - A linear 2-port element can be used:
 - Use a transformer or gyrator

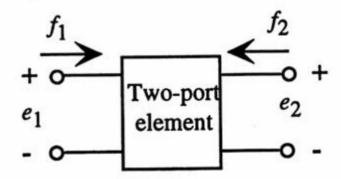


Figure 5.11. General two-port element.

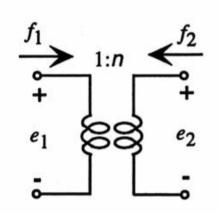
power in = power out NO POWER LOSS

$$e_1 f_1 + e_2 f_2 = 0 (5.41)$$

Transformer

TRANSFORMER:

$$\begin{pmatrix} e_2 \\ f_2 \end{pmatrix} = \begin{pmatrix} n & 0 \\ 0 & -\frac{1}{n} \end{pmatrix} \begin{pmatrix} e_1 \\ f_1 \end{pmatrix} \tag{5.42}$$



$$e_2 = m \cdot e_1$$

$$f_2 = -\frac{1}{n} f_1$$

n = "turns ratio"

Gyrator

GYRATOR:

$$\begin{pmatrix} e_2 \\ f_2 \end{pmatrix} = \begin{pmatrix} 0 & n \\ -\frac{1}{n} & 0 \end{pmatrix} \begin{pmatrix} e_1 \\ f_1 \end{pmatrix} \tag{5.43}$$

$$\begin{array}{c}
f_1 \\
 + \\
 e_1
\end{array}$$
Gyrator

The impedances can be transformed

$$Z_{in}(s) = \frac{Z(s)}{m^2}$$

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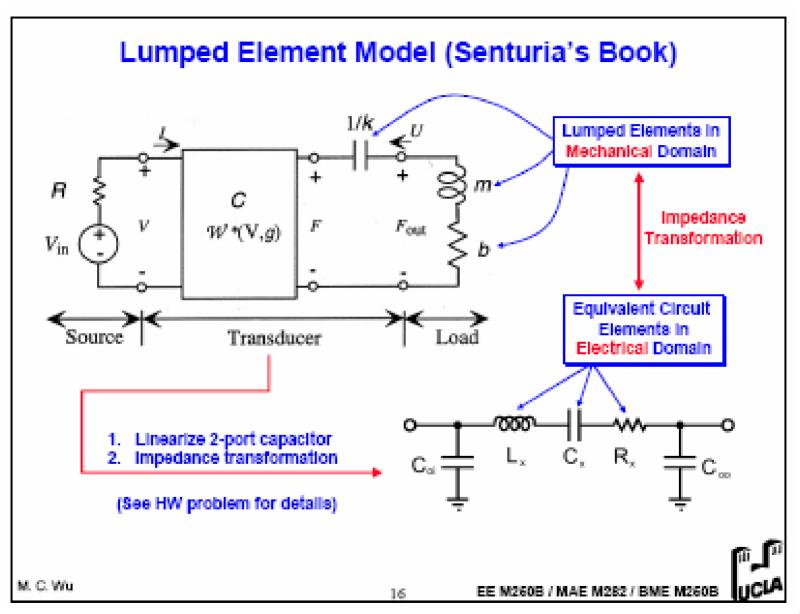
$$Z_{in}(s) = \frac{Z(s)}{m^2}$$

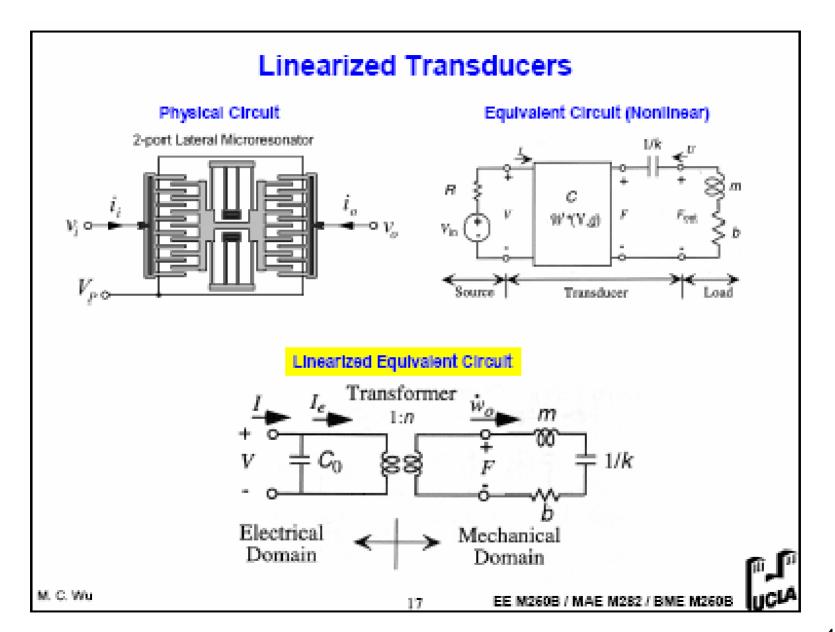
$$Z_{in}(s) = \frac{Z(s)}{m^2}$$
Transformer

n = coupling coefficient between energy domains

$$Z_{in}(s) = \frac{e_1}{f_1}$$

$$Z(s) = \frac{e_2}{-f_2} = \frac{n \cdot e_1}{\frac{1}{n} \cdot f_1} = n^2 \cdot \frac{e_1}{f_1} = n^2 \cdot Z_{in}(s)$$





Procedure

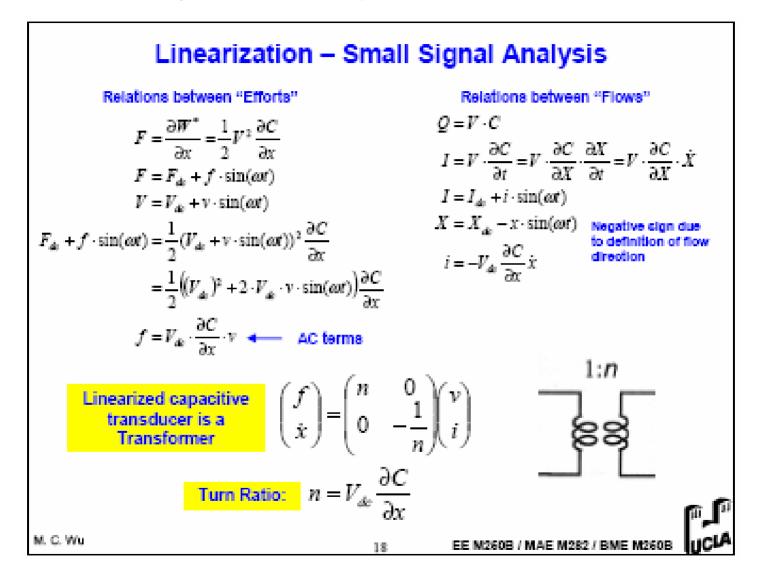
- Investigate relation between "efforts" and "flows" in the 2 domains
- Efforts: calculation procedure
 - 1. Start with an expression for potential energy
 - 2. Calculate force
 - 3. Look at perturbations around the DC-bias
 - 4. Find the relationship between AC-terms
 - → A linear relationship is obtained

Relation between "efforts"

$$\begin{split} F &= \frac{\partial W^*}{\partial x} = \frac{1}{2} V^2 \frac{\partial C}{\partial x} \\ F &= F_{de} + f \cdot \sin(\omega t) \\ V &= V_{de} + v \cdot \sin(\omega t) \\ F_{de} &+ f \cdot \sin(\omega t) = \frac{1}{2} (V_{de} + v \cdot \sin(\omega t))^2 \frac{\partial C}{\partial x} \\ &= \frac{1}{2} \Big((V_{de})^2 + 2 \cdot V_{de} \cdot v \cdot \sin(\omega t) \Big) \frac{\partial C}{\partial x} \\ f &= V_{de} \cdot \frac{\partial C}{\partial x} \cdot v \quad \blacktriangleleft \quad \text{ AC terms} \end{split}$$

effort (mechanical domain) = const. * effort (electrical domain)

Similarly for relationship between FLOWS:



flow (electrical domain) = - const. * flow (mechanical domain)

Current direction, mechanical domain

- Flow in the mechanical domain is defined as positive into the 2-port transducer
- Choose the current to go out of 2-port C. Then we have:
 - Current goes into the electrical domain
 - → creates an attractive force on the comb
 - − → spring stretches
 - → potential energy is built up
 - → equivalent to charging of an 1/k-capacitor
 - → Current increases → charge on the capacitor increases → attractive force increases → displacement (x) decreases

Compatible relations both between "efforts" and "flows"

$$f = V_{de} \cdot \frac{\partial c}{\partial x} \cdot v = n \cdot v \quad den \quad m = V_{dc} \cdot \frac{\partial c}{\partial x}$$

$$i = -V_{dc} \cdot \frac{\partial c}{\partial x} \cdot \dot{x} = -m \cdot \dot{x} \quad \Rightarrow \quad \dot{x} = -\frac{1}{n} \cdot \dot{t}$$

- effort (mechanical domain) = n * effort (electrical domain)
- flow (mechanical domain) = -1/n * flow (electrical domain)
- A linearized capacitive transducer implemented as a transformer can be used!

Impedance Transformation 1:n 🛂 Z(s)Equivalent Impedance In $\begin{pmatrix} f \\ \dot{x} \end{pmatrix} = \begin{pmatrix} n & 0 \\ 0 & -\frac{1}{n} \end{pmatrix} \begin{pmatrix} v \\ i \end{pmatrix}$ Impedance in Electrical Domain Mechanical Domain

$$Z_{in}(s) = \frac{1}{n^2} Z(s)$$

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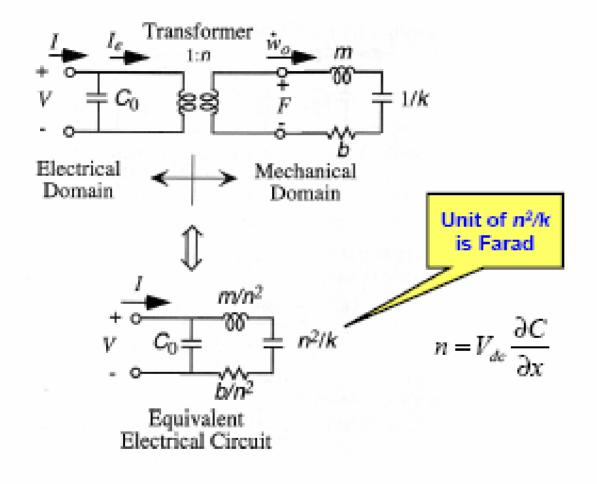
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Transformation of impedances

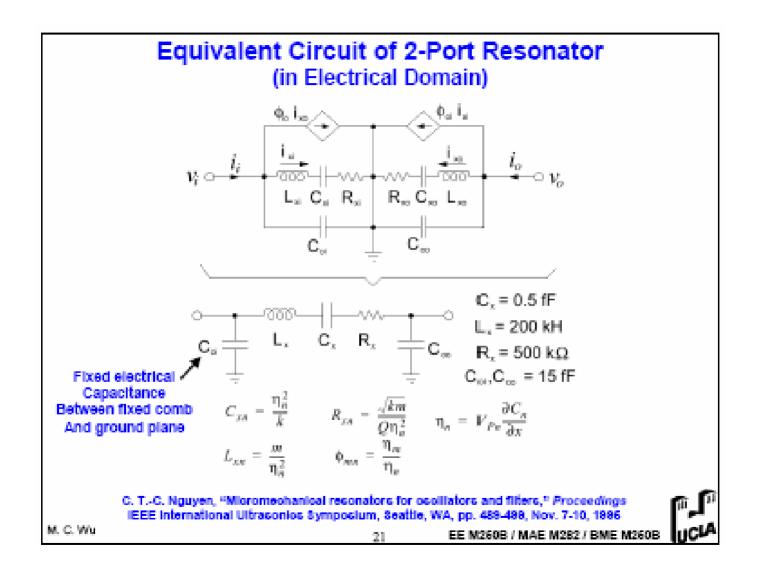
$$Z_{el} = \frac{1}{n^2} \cdot Z_{mek}$$
 Inductor
$$sL_{el} = \frac{1}{n^2} \cdot sL_{mek} = \frac{sm}{n^2} \Rightarrow L_{el} = \frac{m}{n^2}$$
 Resistor
$$R_{el} = \frac{1}{n^2} \cdot R_{mek} = \frac{b}{n^2}$$
 Capacitor
$$\frac{1}{sC_{el}} = \frac{1}{n^2} \cdot \frac{1}{sC_{mek}} = \frac{1}{n^2} \cdot \frac{k}{s} \Rightarrow C_{el} = \frac{n^2}{k}$$

Small Signal Equivalent Circuit of Microresonators



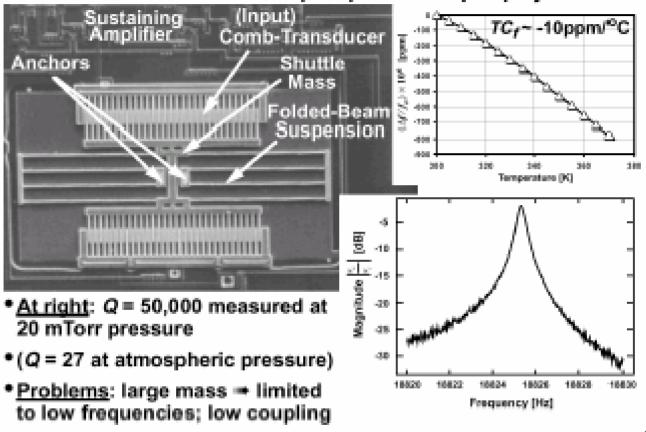


Both methods result in the same equivalent circuit:



Comb-Transduced Folded-Beam Microresonator

Micromachined from in situ phosphorous-doped polysilicon



EE M260B / MAE M282 / BME M260B

M. C. Wu

Comb resonator, summary

- Summary of modeling:
- Force: Fe = ½ dC/dx V ^2 (force is always attractive)
 - Input signal Va * cos (ωt)
 - Fe ~ $Va^2 * \frac{1}{2} [1 + \cos(2\omega t)]$
 - Driving force is 2x input-frequency + DC: NOT DESIRABLE
- Add DC bias, Vd
 - Fe ~ Vd ^2 + 2 Vd * Va * cos ω t + negligible term (2ωt)
 - Keep linearized AC force-component ~ Vd * Va, which oscillates with the same frequency as Va: ω
- C increases when finger-overlap increases (comb moves)
 - $-\epsilon * A/d$ (A = comb-thickness * overlap-length)
- dC/dx = constant for a given design (linear change, C is proportional to length-variation)

Comb-resonator, output current

- A time varying capacitance is established at the output comb
 - Calculate output current when V_d is kept constant and C is varying
 - Io = d/dt (Q) = d/dt (C*V) = Vd * dC/dt = Vd * dC/dx * dx/dt
 - $I_0 = Vd * dC/dx * \omega * x_max$
 - Io plotted versus frequency, shows a BPcharacteristic

Comb-resonator, spring constant

- Spring constant for simple beam deflected to the side
 - k_beam = const * E * t * (w/L) exp3
 - E = Youngs modul, t = thickness, w = width, L = length
- Example in figure 7.9:
 - const = 1 = 4 * $\frac{1}{4}$
 - k_total = 2 * k_beam

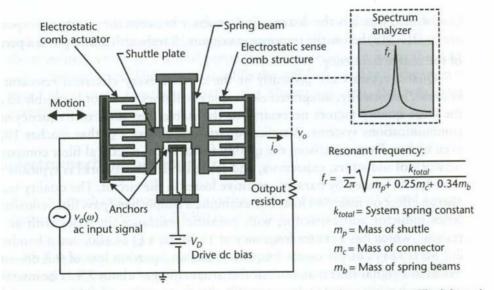


Figure 7.9 Illustration of a micromachined folded-beam comb-drive resonator. The left comb drive actuates the device at a variable frequency ω . The right capacitive-sense-comb structure measures the corresponding displacement by turning the varying capacitance into a current, which generates a voltage across the output resistor. There is a peak in displacement, current, and output voltage at the resonant frequency.

Design parameters

- To obtain a higher resonance-frequency:
- Total spring constant must increase
- Dynamic mass must decrease
 - Difficult to achieve because a minimum number of fingers are needed
 - To have good electrostatic coupling (voltage → force)
 - Process resolution determines how small the lateral structures can be fabricated (geometrical design rules)
- Frequency can be increased by using another material with larger E/p than Si
 - E/ρ is a measure of the spring constant relative to weight
 - Elastic modulus versus material density
 - Aluminum and titanium has E/ρ lower than Si
 - Si carbide, poly diamond has E/ρ higher than for Si (poly diamond is a research topic)